

## On Chip Transmission Line Models in 65nm CMOS Technology with Multilevel Metallization Process

**Authors :** Arthi R., Christopher S., R. David Koilpillai

**Abstract :** In this paper, two on-chip compact transmission lines (TLs) based on the coplanar waveguide (CPW) and microstrip designs are proposed for the 65nm Complementary Metal-Oxide-Semiconductor (CMOS) technology with multilevel metallization process. These transmission lines are analysed using High-Frequency Structure Simulator (HFSS) and 3D electromagnetic full wave simulator. The performance of the transmission line is improved using air gap-based structures within the constraints of fabrication techniques. Through this work it is established that for the 65 nm CMOS technology process, both TL models give a comparable insertion loss performance of  $< 1.58$  dB/mm over the band of 80GHz. However, it is found when matched for a characteristic impedance of  $50\Omega$ , the coplanar waveguide-based TL gives a reflection coefficient of about -30dB and the microstrip line-based TL gives only about -16dB over the 80GHz band. This work also brings out that at low frequency, both the TLs can be used where the reflection coefficient is  $< -25$ dB but at high frequency, the coplanar waveguide based TLs are the best suited with small penalty of increased area.

**Keywords :** coplanar waveguide, microstrip line, monolithic microwave integrated circuit, multilevel metallization process, characteristic impedance

**Conference Title :** ICICDT 2025 : International Conference on Integrated Circuit Design and Technology

**Conference Location :** Paris, France

**Conference Dates :** January 30-31, 2025